AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application.

Listing of Claims:

Claims 1-30. (Canceled).

31. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod–like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of said shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate.

32. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod–like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter

sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of said shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, and wherein said rod-like electrodes are configured to be connected to wiring so that said electrostatic chuck will be mono-pole type or bi-pole type.

33. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod–like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of said shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are

comprised of rod-like base materials, and thermally sprayed films including high-purity ceramics are formed on said rod-like base materials.

34. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod–like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of said shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are comprised of rod-like base materials, wherein cross-sections of said rod-like base materials are in stepped shapes, and wherein said rod-like electrodes are arranged with a predetermined gap (clearance) between adjacent rod-like electrodes.

35. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod–like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter

sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are comprised of rod-like base materials, and cross-sections of said rod-like base materials are arranged like roofing tiles, each having a curved convex portion on one side and a curved concave portion on the other side, and wherein each of said convex portions is arranged with a predetermined gap (clearance) between said convex portion and said concave portion of an adjacent rod-like electrode.

36. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod–like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that

one of said shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are comprised of rod-like base materials, and said rod-like base materials include high-purity isotropic graphite.

37. (Currently Amended) An electrode structure for an electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrode structure being comprised of a plurality of rod-like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when a ~~rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, and

wherein each of the rod-like electrodes includes high-purity ceramic that is thermally sprayed on a surface of rod-like base materials.

38. (Previously Presented) An electrode structure according to claim 37, wherein cross-sections of said base materials are in rectangular shapes.

39. (Previously Presented) An electrode structure according to claim 37, wherein cross-sections of said base materials are in rectangular shapes with wider widths than lengths.

40. (Previously Presented) An electrode structure according to claim 37, wherein cross-sections of said base materials are in stepped shapes.

41. (Previously Presented) An electrode structure according to claim 37, wherein cross-sections of said base materials are arranged like roofing tiles having a curved convex portion on one side and a curved concave portion on the other side.

42. (Previously Presented) An electrode structure according to claim 37, wherein said base materials are comprised of high-purity isotropic graphite.

43. (Currently Amended) A treating system provided with a rectangular substrate stage for receiving a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod–like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of the

rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate.

44. (Currently Amended) A treating system provided with a rectangular substrate stage for receiving a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod–like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, and wherein said rod-like electrodes are configured to be connected to wiring so that said rod-like electrodes will be mono-pole or bi-pole type.

45. (Currently Amended) A treating system provided with a rectangular substrate stage for electrostatically attracting a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod–like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are

parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of said rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate , wherein said rod-like electrodes are comprised of rod-like base materials, and wherein thermally sprayed films comprised of high-purity ceramics are formed on surfaces of said rod-like base materials.

46. (Currently Amended) A treating system provided with a rectangular substrate stage for electrostatically attracting a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod–like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of said rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrode extends in parallel to a longer side of said rectangular substrate , wherein said rod-like electrodes are comprised of rod-like base materials,

wherein cross-sections of said rod-like base materials are in stepped shapes, and wherein said rod-like electrodes are arranged with a predetermined gap (clearance) between adjacent rod-like electrodes.

47. (Currently Amended) A treating system provided with a rectangular substrate stage for electrostatically attracting a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod–like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of said rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate , wherein said rod-like electrodes are comprised of rod-like base materials, wherein cross-sections of said rod-like base materials are arranged like roofing tiles, each having a curved convex portion on one side and a curved concave portion on the other side, and wherein said convex portion is arranged with a predetermined gap (clearance) between said convex portion and said concave portion of an adjacent rod-like electrode.

48. (Currently Amended) A treating system provided with rectangular substrate stage for electrostatically attracting a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod–like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of said rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate , wherein said rod-like electrodes are comprised of rod-like base materials, and wherein said rod-like base materials include high-purity isotropic graphite.